

Title:

Park Systems AFM NX10

Sub-title:

Atomic Force Microscope: a powerful measurement tool for surface analysis.

General description:

This instrument is designed to produce inherently distortion-free and reproducible images. Park Afm system has a unique scanning mode, (True Non-Contact™ mode), that produces accurate, high-resolution data by preventing destructive tip-sample interaction during scanning. (Opzionale)

Features:

- Decoupled XY and Z Scanners
- Motorized XY and Z stage.
- XY stage travel range: 20 mm x 20 mm
- Z stage travel range: 25 mm
- Focus stage travel range: 15 mm
- Scan Range, 50 μm x 50 μm
- Contact mode, tapping mode and True Non-Contact™ mode
- Nanoindentation and PinPoint Nanomechanical Mode
- Electrostatic Force Microscopy (EFM), Piezo Force Microscopy (PFM), Magnetic Force Microscopy (MFM)
- Possibility of using pre-assembled cantilevers
- Automated cantilever approach
- Liquid probe

Applications:

- Thin film and coatings
- Polymers
- Materials science, nanotechnology
- Surface chemistry
- Piezoelectric and ferroelectric materials
- Cell and molecular biology
- Semiconductor science and technology
- Molecular biology